

edited by **Anthony H. W. Choi**

Handbook of

OPTICAL MICROCAVITIES





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Contents

<i>Preface</i>	xiii
1. Photonic Crystal Microcavities and Microlasers	1
<i>Tomoyuki Yoshie</i>	
1.1 Introduction	1
1.2 Photonic Crystal Microcavity Modes	3
1.2.1 1D Photonic Crystal Microcavity	3
1.2.2 2D Photonic Crystal Slab Microcavity	5
1.2.3 3D Photonic Crystal Microcavity	8
1.2.4 Surface Bloch Mode Microcavity	10
1.3 Optically Pumped Photonic Crystal Microlasers	12
1.4 High-Speed Photonic Crystal Microlasers	14
1.5 Current-Injection Photonic Crystal Microlasers	16
1.6 Optical Sensing in Photonic Crystal Microcavity	18
1.7 Microcavity-QED in Photonic Crystal	20
1.8 Conclusions	21
2. Simulation of Planar Photonic Resonators	27
<i>Stefan Declair and Jens Förstner</i>	
2.1 Maxwell's Equations	28
2.2 Numerics with Maxwell's Equations: The FDTD	31
2.2.1 Update Equations of the FDTD	32
2.2.2 Accuracy and Stability	35
2.2.3 Subpixel Averaging for Isotropic Dielectric Media	39
2.2.4 CPML: Truncate the Computational Volume	41
2.3 Nanoscale Optical Resonators	43
2.3.1 The MD Resonator	44
2.3.1.1 Simulation of an MD resonator	48

2.3.2	The Photonic Crystal Cavity	50
2.3.2.1	Simulation of a photonic crystal cavity	56
2.4	Active Material	59
2.4.1	The Quantum Dot Model	60
2.4.2	Quantum Dots in the FDTD: Back-Coupling to the Electromagnetic Field and Limits	62
2.4.3	Nonlinearities in Quantum Dots: Rabi Oscillations	66
2.4.4	A Single Quantum Dot in a Photonic Crystal Cavity	69
2.4.5	Multiple Quantum Dots in a Photonic Crystal Cavity	72
3.	Ultraviolet GaN-Based Lasers with Micro-/Nanostructures	83
	<i>Hao-Chung Kuo, Min-Hsiung Shih, Chien-Chung Lin, Tien-Chang Lu, Shing-Chung Wang, Chun-Yen Chang, Cheng-Chang Chen, and Yow-Gwo Wang</i>	
3.1	Introduction to GaN-Based Lasers	83
3.1.1	Nitride-Based Semiconductor Lasers	83
3.1.2	Edge-Emitting Lasers	84
3.2	Surface-Emitting Lasers	85
3.2.1	Vertical Cavity Surface-Emitting Lasers	85
3.2.1.1	Fully epitaxial grown VCSEL structure	88
3.2.1.2	VCSEL structure with two dielectric mirrors	88
3.2.1.3	VCSEL structure with hybrid mirrors	89
3.2.2	Design and Fabrication of the the Hybrid-Type GaN-Based VCSELs	90
3.2.3	The Optically Pumped Hybrid-Type GaN VCSELs at Room Temperature	91
3.2.4	The Optically Pumped All Dielectric-Type GaN VCSELs at Room Temperature	98

3.2.5	Result and Discussion	102
3.3	Fabrication and Characteristics of GaN-Based Microdisk Lasers with Ultraviolet Distributed Bragg Reflectors	106
3.3.1	Ultraviolet AlN/AlGa _N DBR	107
3.3.2	Design and Growth of Ultraviolet AlN/AlGa _N DBR	107
3.3.3	Analysis of Reflectance Spectra	108
3.3.4	The Set-Up of Microphotoluminescence	110
3.3.5	Fabrication Procedures of Microdisk Lasers	110
3.3.6	Measurement Results and Analysis	112
3.4	The Study of Metal-Coated GaN Nanostripe Lasers	116
3.4.1	Fabrication of Metal-Coated GaN Nanostripe	116
3.4.2	Characteristics of Optically Pumped Nanostripe Lasers	119
3.5	Conclusions	123
3.5.1	Vertical Cavity Surface-Emitting Laser	123
3.5.2	GaN-Based Microdisk Laser	124
3.5.3	Metal-Coated GaN Nanostripe Lasers	124
4.	(Al,Ga)N Microdisk Cavities	131
	<i>Sylvain Sergent and Fabrice Semond</i>	
4.1	Introduction	131
4.2	Resonant Modes in Microdisks	132
4.2.1	Effective Index	134
4.2.2	Whispering Gallery Modes	137
4.2.3	Quality Factor and Origin of Losses	141
	4.2.3.1 Intrinsic quality factor	141
	4.2.3.2 Absorption losses	142
	4.2.3.3 Scattering losses	143
4.3	Fabrication of Microdisk Resonators	144
4.3.1	Growth of Thin GaN Quantum Dot Stacks on Silicon Substrates	145

4.3.2	Processing of Microdisks and Structural Properties	146
4.4	Optical Properties	149
4.4.1	$\text{Al}_{0.5}\text{Ga}_{0.5}\text{N}$ Microdisks	149
4.4.2	AlN Microdisks	150
4.5	Conclusion	152
5.	MOCVD Growth of Nitride DBRs for Optoelectronics	157
	<i>Tao Wang</i>	
5.1	Introduction	157
5.2	Nitride DBRs	160
5.2.1	Lattice-Mismatched DBRs	162
5.2.2	Crack Issues in Growth of Lattice-Mismatched DBRs	162
5.2.3	Strain Management in Growth of Lattice-Mismatched DBRs	165
5.2.4	Structure Design in Growth of Lattice-Mismatched DBRs	172
5.3	Lattice-Matched DBRs	175
5.3.1	Air Gap-Based DBRs	180
5.4	DBRs for LDs	186
5.4.1	InGaN/GaN-Based Visible VCSELs	186
5.4.2	AlGaIn/GaN-Based UV VCSELs	196
5.4.3	III-Nitride-Based Polariton Laser	198
5.5	DBRs for Other GaN-Based Optoelectronics	200
5.6	Summary	202
6.	III-Nitride Photonic Crystal LEDs for Lighting Applications	211
	<i>T. N. Oder, J. Y. Lin, and H. X. Jiang</i>	
6.1	Introduction	212
6.2	Lighting Sources and LEDs	215
6.2.1	Light Source in Human History	215
6.2.2	LEDs versus Other Lighting Sources	217

6.3	First III-Nitride PC-LED Work	219
6.3.1	Introduction	219
6.3.2	Optically Pumped III-Nitride PC LEDs	220
6.3.3	Electrically Pumped III-Nitride PC LEDs	226
6.4	Current Approaches Using Embedded PCs	234
6.5	Concluding Remarks	236
7.	Nanostructures in the III-Nitride/Silicon Material System	245
	<i>Yongjin Wang</i>	
7.1	Freestanding III-Nitride Resonant Gratings	246
7.1.1	III-Nitride Resonant Structures Fabricated by a Front-side Process	254
7.1.2	III-Nitride Resonant Structures Grown on Freestanding HfO ₂ Structures	259
7.2	Freestanding Circular III-Nitride Gratings	264
7.2.1	Freestanding III-Nitride Subwavelength Nanostructures	269
7.2.2	Patterned Growth of InGaN/GaN MQWs	274
7.2.3	Freestanding III-Nitride Nanocolumn Slab with Bottom Subwavelength Nanostructures	281
8.	Coupling of a Light Emitter with Surface Plasmon Induced on a Metal Nanostructure for Emission Enhancement	293
	<i>Yang Kuo, Horng-Shyang Chen, Dong-Mong Yeh, Yu-Lung Jung, Chia-Phen Chen, Yean-Woei Kiang, and Chih-Chung Yang</i>	
8.1	Introduction	294
8.2	LSP Resonance of Surface Metal Nanoparticles	299
8.3	LSP Resonance of Embedded Metal Nanoparticles	303
8.4	SP Resonance of Metal Nanodisks Penetrating into Semiconductor	307
8.5	Discussions and Summary	310

9. Nanosphere-Patterned Gallium Nitride Optical Microcavities 315

Kwai Hei Li and Anthony H. W. Choi

9.1	Introduction	315
9.2	Nanosphere Lithography	317
9.2.1	Process Development	318
9.2.2	NSL-Patterned Nanostructures on Nitride Material	320
9.3	Photons Confinement in Various Sphere-Patterned Cavities	322
9.3.1	Photonic Crystal Band-edge Lasing from Nanopillar Array	322
9.3.2	Whispering Gallery Mode Lasing from Sphere-Patterned Cavities	329
9.3.2.1	Overview	329
9.3.2.2	UV single-mode lasing from metal-clad pillar	330
9.3.2.3	High-Q WG mode from nanoring array	337
9.4	Conclusion	344

10. Epitaxial Lift-Off of GaN Films 349

Keyan Zhang and Soo Jin Chua

10.1	Introduction	350
10.2	Lift-Off Techniques and Their Applications	351
10.2.1	Laser Lift-Off	351
10.2.2	Photo-Assisted Electrochemical Lift-Off	354
10.2.3	Electrochemical Lift-Off	358
10.2.4	Wet Chemical Lift-Off Using Sacrificial Layer	363
10.2.5	Nanoepitaxial Lift-Off	364
10.2.6	Mechanical Lift-Off	368
10.2.7	Lift-Off of GaN-on-Silicon	370

10.2.8	Comparison of the Merits of Different Etching Techniques	371
10.3	Summary and Outlook	372
11.	Gallium Arsenide Disk Optomechanical Resonators	381
	<i>Jin Chua Lu Ding, Christophe Baker, Alessio Andronico, David Parrain, Pascale Senellart, Aristide Lemaitre, Sara Ducci, Giuseppe Leo, and Ivan Favero</i>	
11.1	Introduction	381
11.2	Fundamentals of Whispering Gallery Disk Resonators	384
11.2.1	Terminology of Whispering Gallery Modes in Disk Resonators	384
11.2.1.1	Quality factor, photon lifetime, and optical losses	385
11.2.1.2	Free spectral range, group velocity, round-trip time, and finesse	387
11.2.1.3	Effective mode volume	388
11.2.2	Eigenvalue Equations for WGMs	388
11.2.2.1	The semi-analytical effective index approach	390
11.2.2.2	The finite-element approach	393
11.2.3	Mode Coupling between Waveguide and Disk Resonator	396
11.2.3.1	The transfer-matrix description of disk-guide evanescent coupling	396
11.2.3.2	The coupling of modes in time	398
11.2.4	Backscattering and Doublet Splitting	402
11.3	Nanofabrication of GaAs Disks and Optical Fiber Tapers	404
11.3.1	Nanofabrication of a GaAs Disk	404
11.3.2	Fabrication of Tapered Nanofibers	405
11.4	Optical Spectroscopy of GaAs Disks Resonators	409

11.4.1	Experimental Set-Up	410
11.4.2	Identification of WGMs	410
11.4.3	Adjustable Evanescent Coupling Experiments	413
11.4.4	Optical Gradient Force in Evanescent Coupling Experiments	415
11.4.5	Statistical Analysis of Nanofabricated GaAs Disks	417
11.5	Optomechanics of GaAs Disk Resonators	421
11.5.1	Experimental Optomechanics of GaAs Disk Resonators	422
11.5.2	Mechanical Modes and Optomechanical Coupling in GaAs Disk Resonators	424
11.5.3	Quantitative Estimation of the Optomechanical Coupling	428
11.6	Summary and Outlook	432

12. Whispering Gallery Mode in ZnO with Hexagonal Cross Section 441

Rui Chen, Van Duong Ta, and Handong Sun

12.1	Introduction	442
12.2	Experimental and Instrumental Methodology	444
12.2.1	Material Growth	444
12.2.2	Optical Characterization	445
12.3	Key Research Findings	446
12.3.1	Spontaneous Emission	447
12.3.2	WGM Lasing	450
12.3.2.1	Lasing mechanism	451
12.3.2.2	Lasing characteristics	456
12.3.2.3	Multi-photon absorption induced lasing	459
12.3.3	Exciton Polaritons	459
12.4	Potential Applications	462
12.4.1	Refractive Index Sensor	462
12.4.2	Microlaser Diode	463
12.5	Conclusions and Future Perspective	465

13. Nanoscale Semiconductor Ring Lasers 473

Min W. Kim and P.-C. Ku

13.1	Introduction	473
13.2	Scaling Properties of Nanoring Lasers and the Role of Metals	475
13.3	Design of Nanoring Lasers	479
13.3.1	Control of Output Wavelength	480
13.3.2	Metal Thickness	481
13.3.3	Output Coupling	483
13.4	Fabrication and Characterization of Nanoring Lasers	485
13.5	Summary	491

<i>Index</i>	495
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Preface

An optical microcavity constitutes an integral part of a laser diode, confining light within an optical structure to establish optical resonances. At present, edge-emitting and vertical-cavity surface-emitting lasers are the most common types of laser diodes in the market, both of which are based on Fabry-Pérot cavities. However, novel forms of laser structures, based on alternative modes of optical confinement such as whispering-gallery modes and photonic bandgaps have been demonstrated in recent years, allowing light to be confined within smaller dimensions with high finesse.

Apart from different mechanisms of optical confinement, laser diodes based on different material systems give rise to devices operating at different wavelengths for different applications. For instance, the short-wavelength violet laser diodes based on the III-nitrides have been widely used for high-density optical storage in blu-ray players, while long-wavelength As-based infrared (IR) laser diodes are deployed in optical communication networks.

The chapters in this book cover a comprehensive range of topics pertaining to resonance in optical cavities by leading researchers in the field. Subjects include theory, design, simulation, fabrication, and characterization of micrometer and nanometer scale structures and devices that support cavity resonance via various mechanisms such as Fabry-Pérot, whispering gallery, photonic bandgap, and plasmonic modes. Optical cavities resonating from UV to IR wavelengths based on prominent III-V material systems, including nitrides of Al, In, and Ga; ZnO; and GaAs, are covered in this book.

The book begins with a comprehensive review of photonic crystal microcavities and microlasers, followed by a discussion on the simulation of planar photonic resonators. Chapters 3 to 10 pertain to optical cavities based on the III-nitride material system, including that of UV lasers; nitride microdisk cavities grown on Si substrate; MOCVD-grown nitride distributed Bragg reflectors; photonic crystal light-emitting diodes (LEDs); nanostructures in GaN-Si materials; light-coupling to surface plasmons; nanosphere-

patterned microcavities; and epitaxial lift-off of GaN thin films. Chapters 11 and 12 deal with optical microcavities based on GaAs and ZnO, respectively, while Chapter 13 analyzes nanoscale ring lasers.

It was a privilege to take responsibility for putting together this book, with the honor to invite distinguished researchers in field to contribute their expertise and insights in this intriguing technology. I would like to express my immense gratitude to all the contributors of the book. Without their kind and strong support, the project would not have been accomplished.

Anthony H. W. Choi

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